

FIG 1

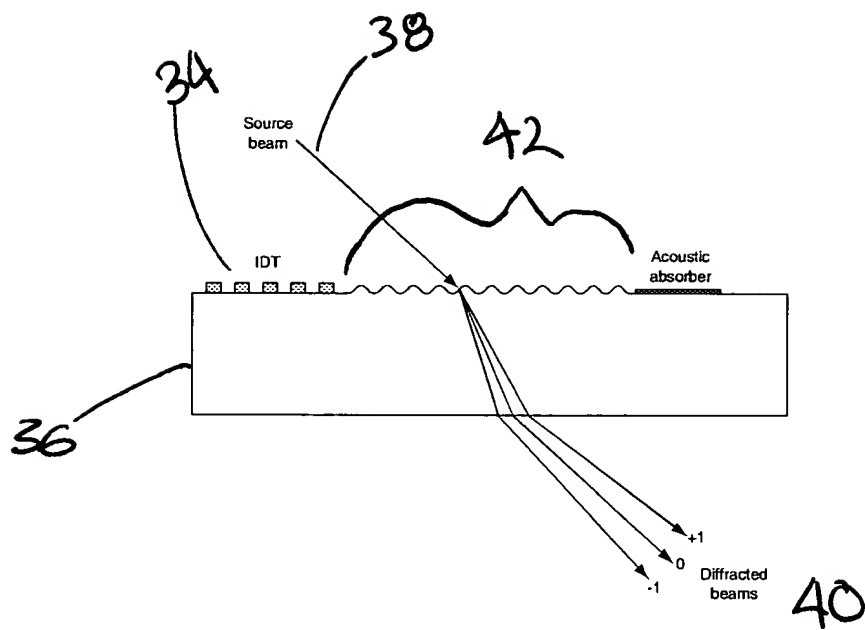
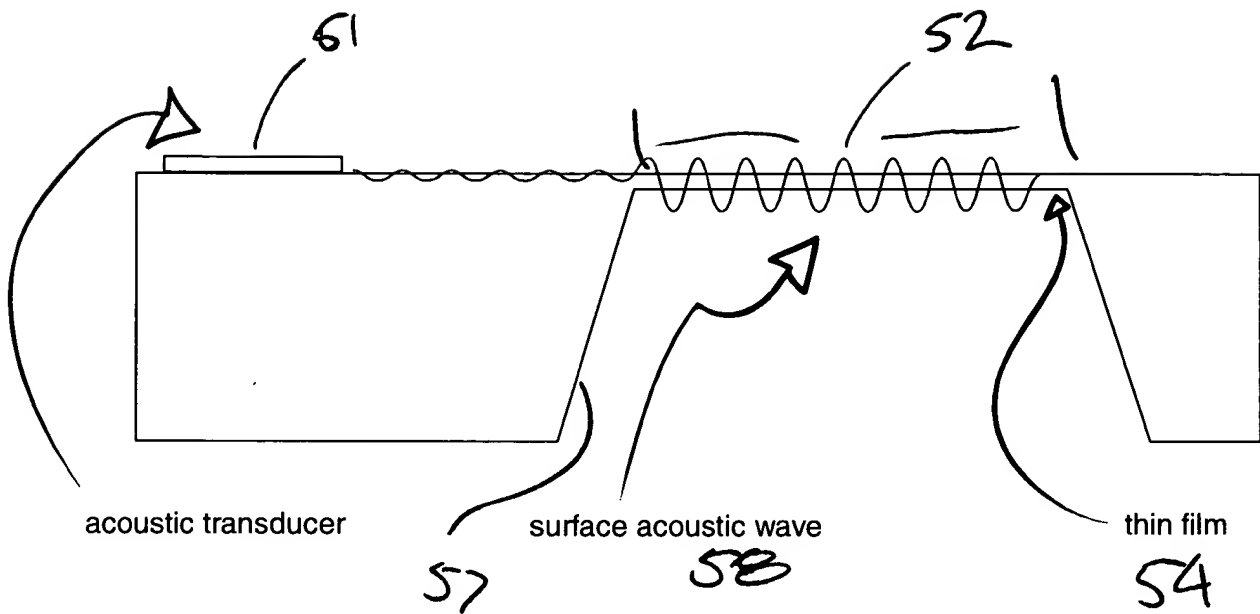


FIG 2

FIG. 3 is a schematic diagram of a surface acoustic wave device. The device includes a substrate 50, a thin film 54, and an acoustic transducer 51. A surface acoustic wave 52 is shown propagating along the surface of the thin film 54. The acoustic transducer 51 is positioned to generate and detect the surface acoustic wave 52. The thin film 54 is disposed on the substrate 50. The surface acoustic wave 52 is represented by a wavy line along the interface between the thin film 54 and the substrate 50. The acoustic transducer 51 is shown as a rectangular block on the surface of the thin film 54. The substrate 50 is the base layer of the device. The thin film 54 is a layer of material deposited on the substrate 50. The surface acoustic wave 52 is a mechanical wave that travels along the surface of the thin film 54. The acoustic transducer 51 is used to convert electrical signals into mechanical waves and vice versa.



50

FIG 3

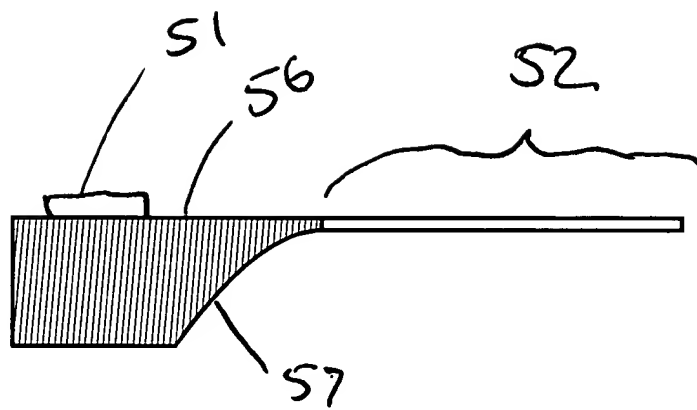


FIG 3b

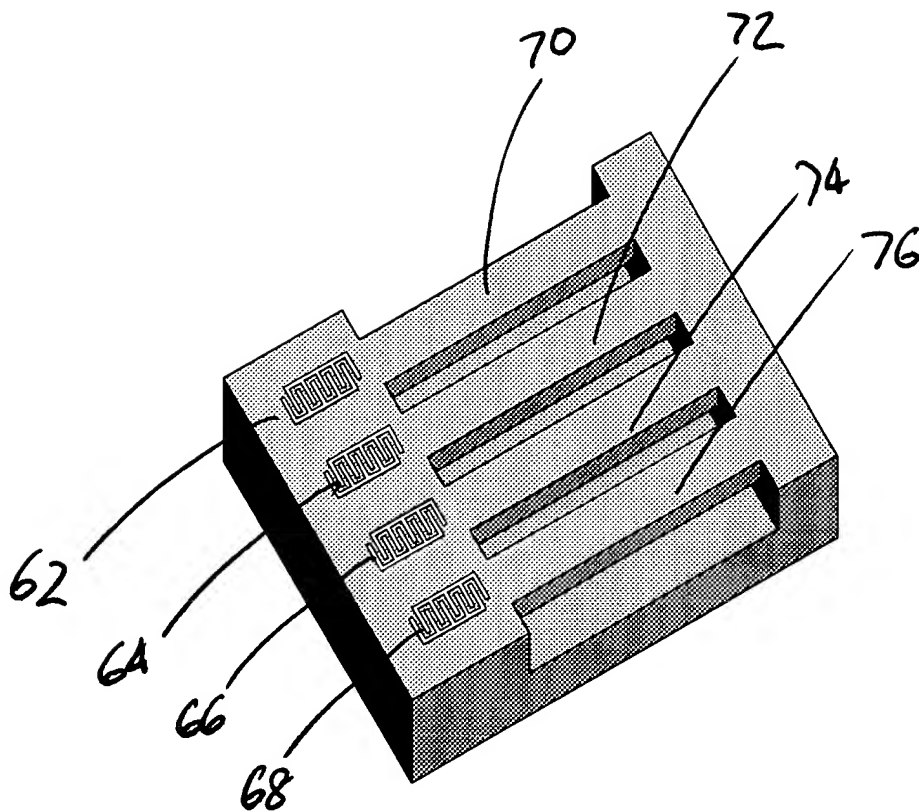


FIG 4a

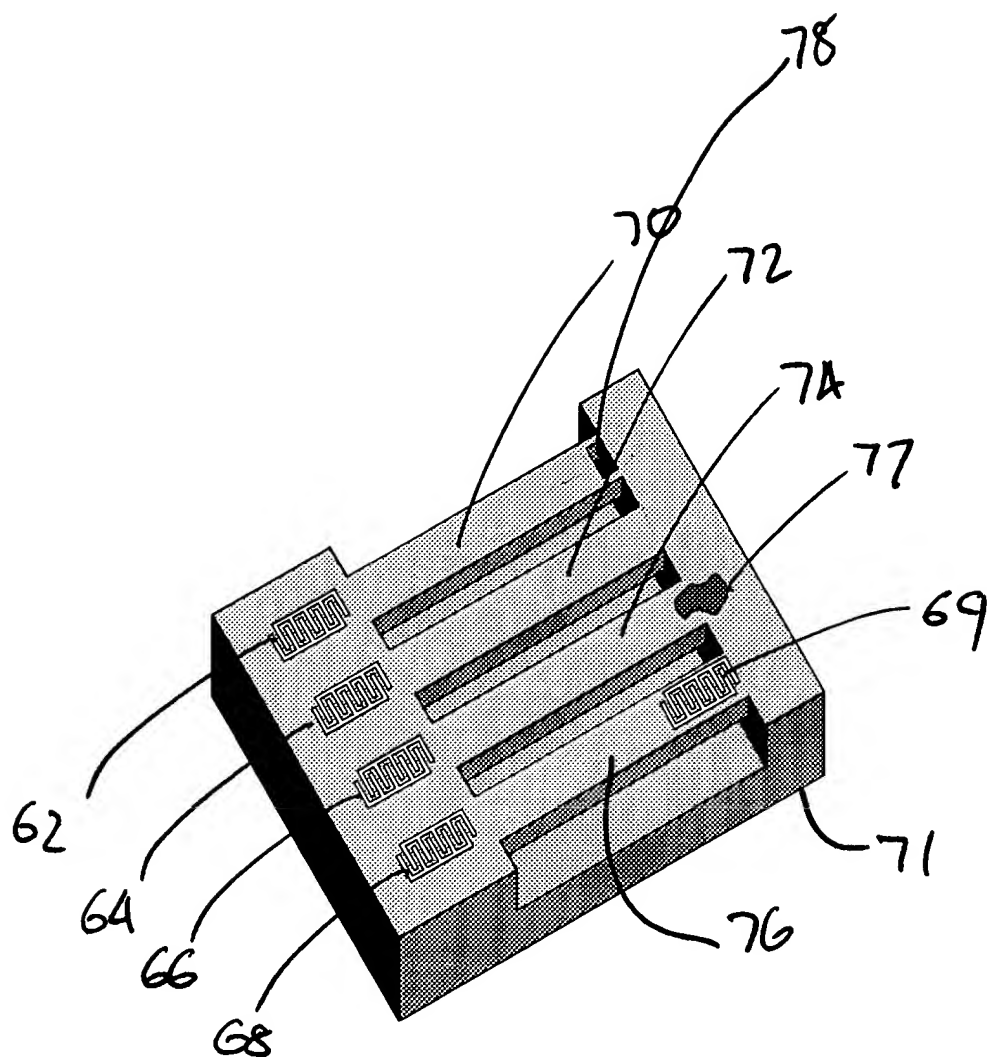


FIG 4b

IDT configurations

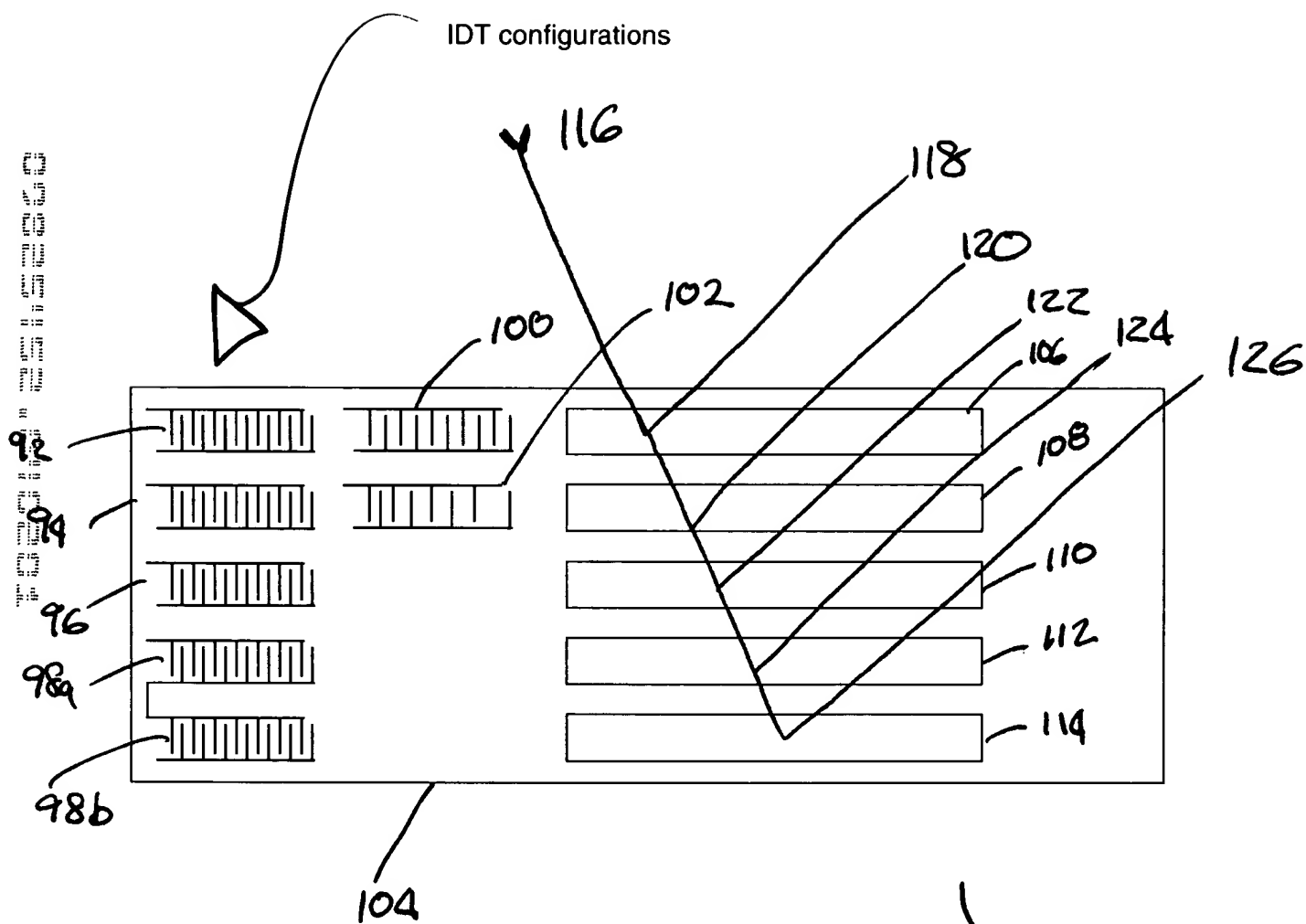
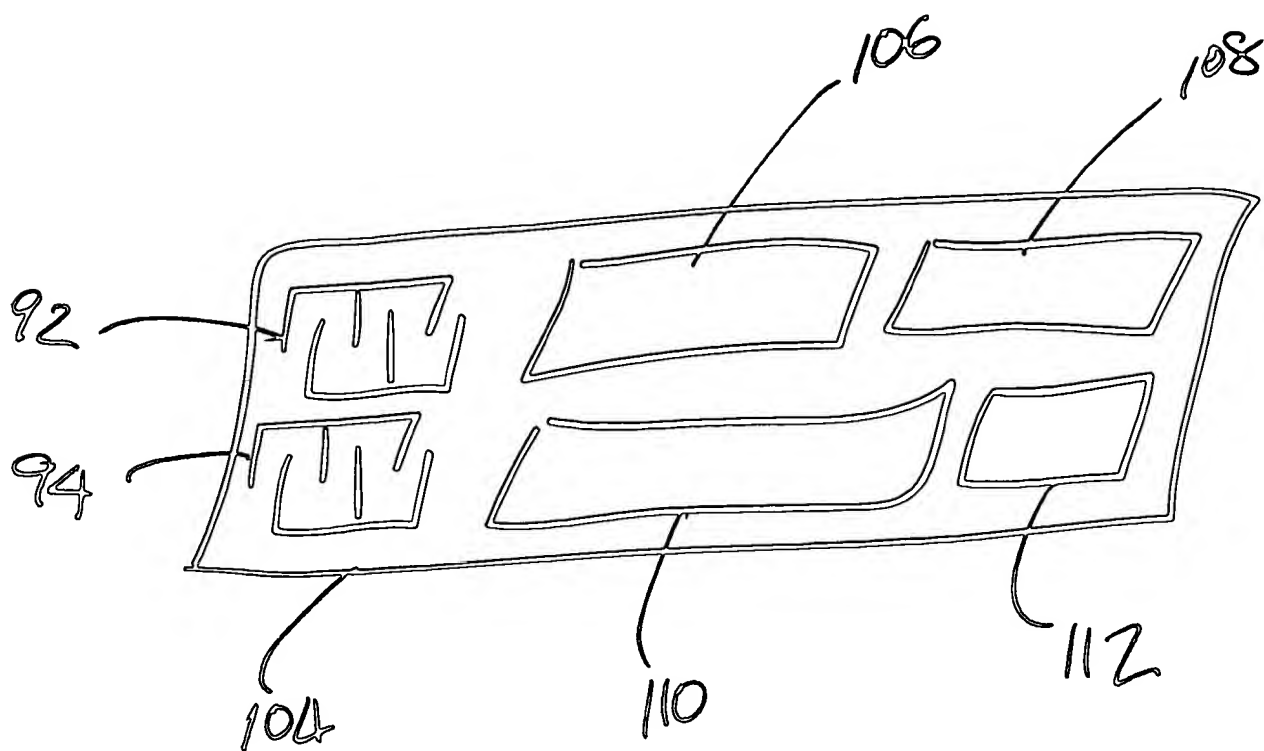


FIG 5a

FIG. 5B is a perspective view of the control panel 100 of the device 10, showing the control panel 100 with the display 102, the touch screen 104, the touch screen 106, the touch screen 108, the touch screen 110, and the touch screen 112.



5B

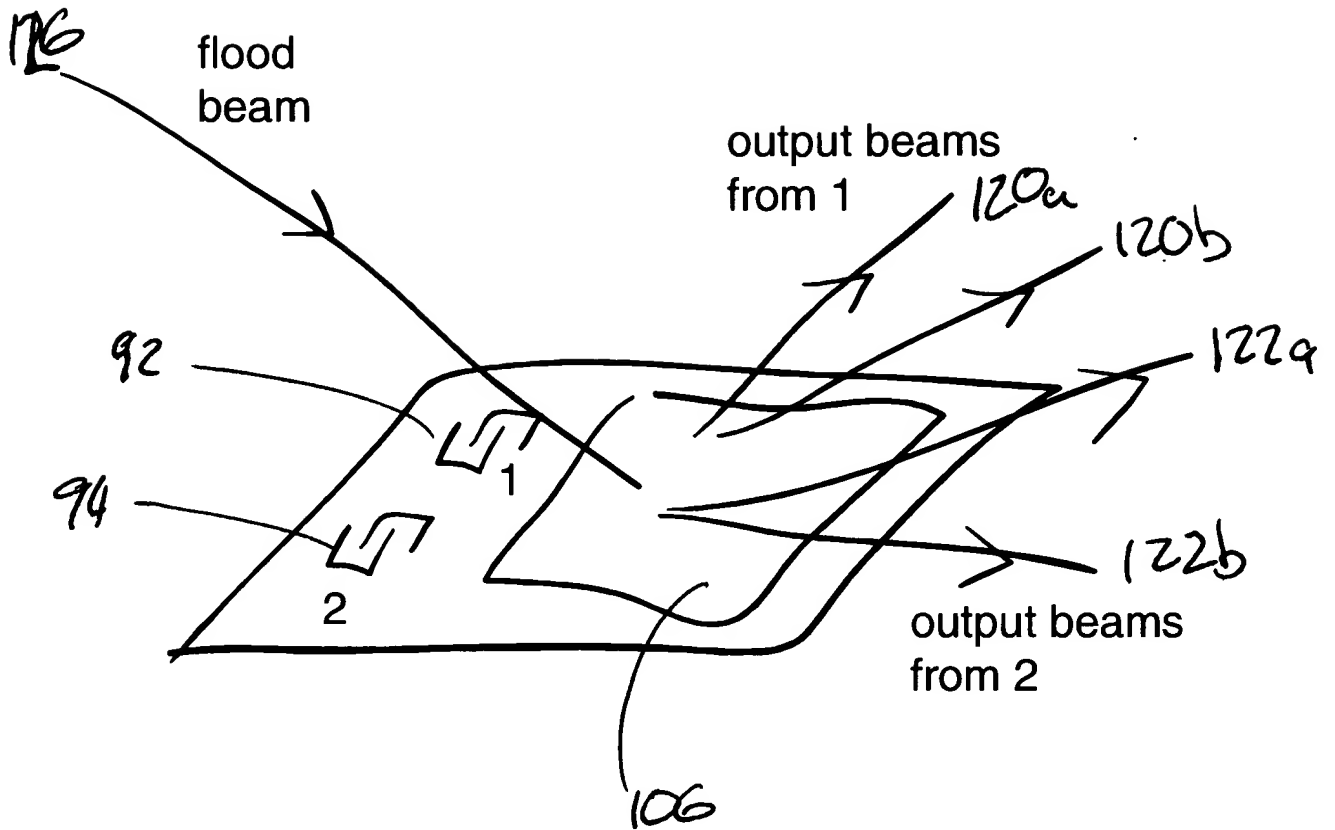


FIG 5C

multiple
input
beams

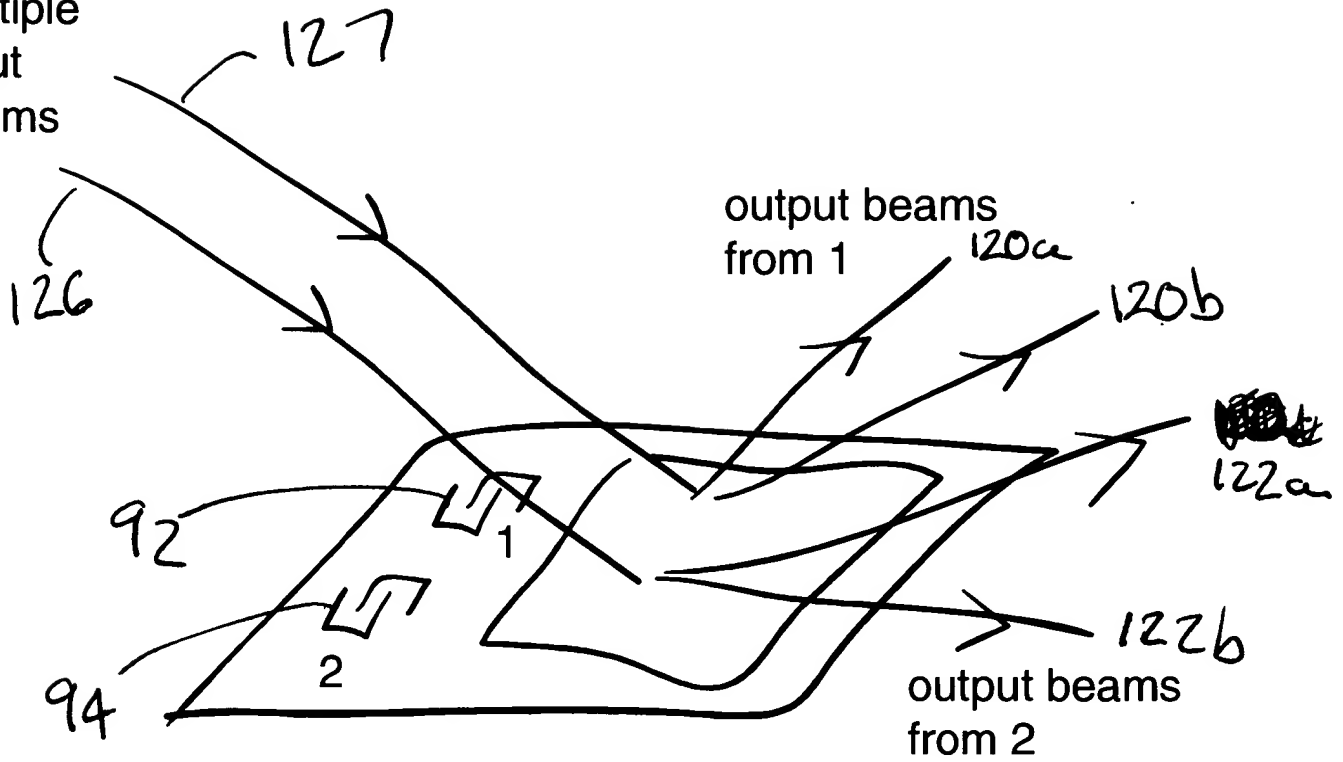


FIG 5d

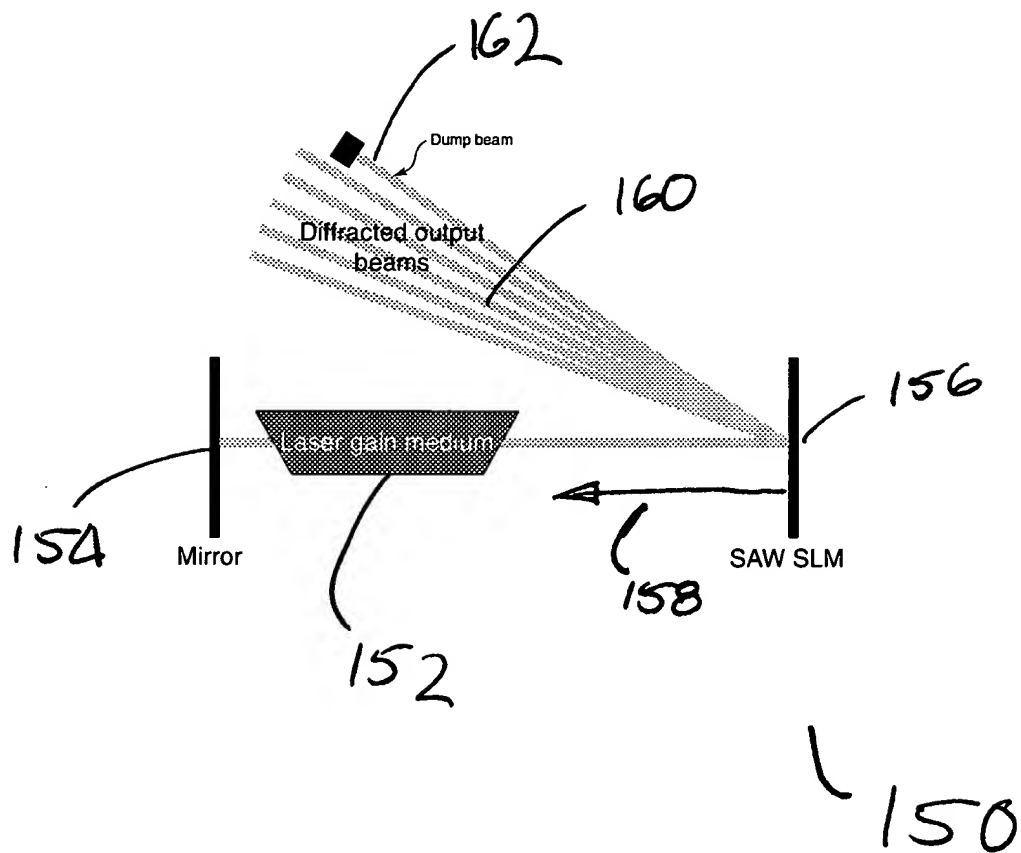


FIG 6

FIG. 7 is a perspective view of a fiber optic system 170. The system 170 includes a source 172, a collimating lens 174, a beam splitter 176, and receiving fibers 178. The source 172 includes source fibers 172a, 172b, and 172c. The collimating lens 174 includes collimating lenses 174a, 174b, and 174c. The beam splitter 176 includes beam splitters 176a, 176b, and 176c. The receiving fibers 178 include receiving fibers 178a, 178b, and 178c.

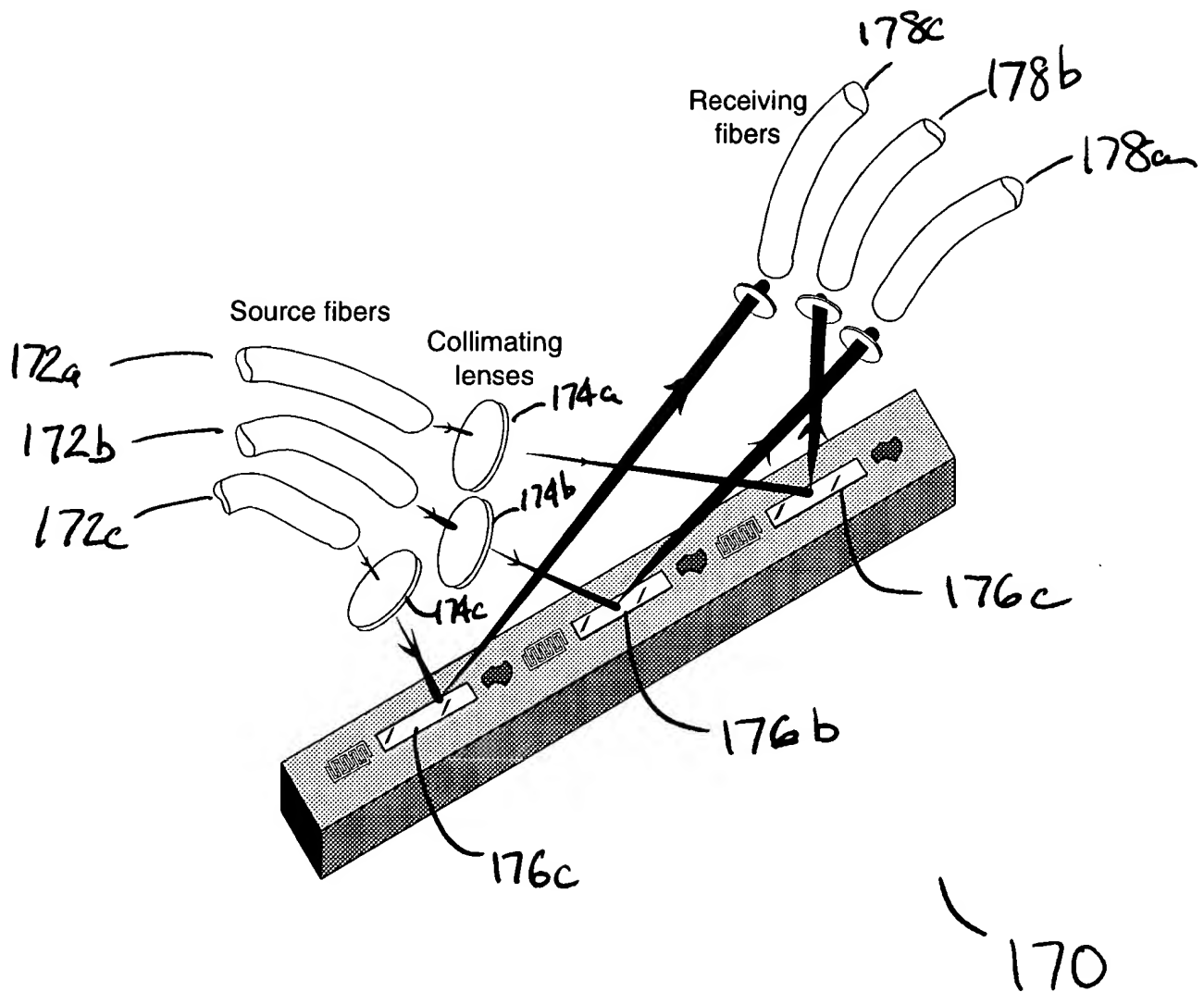
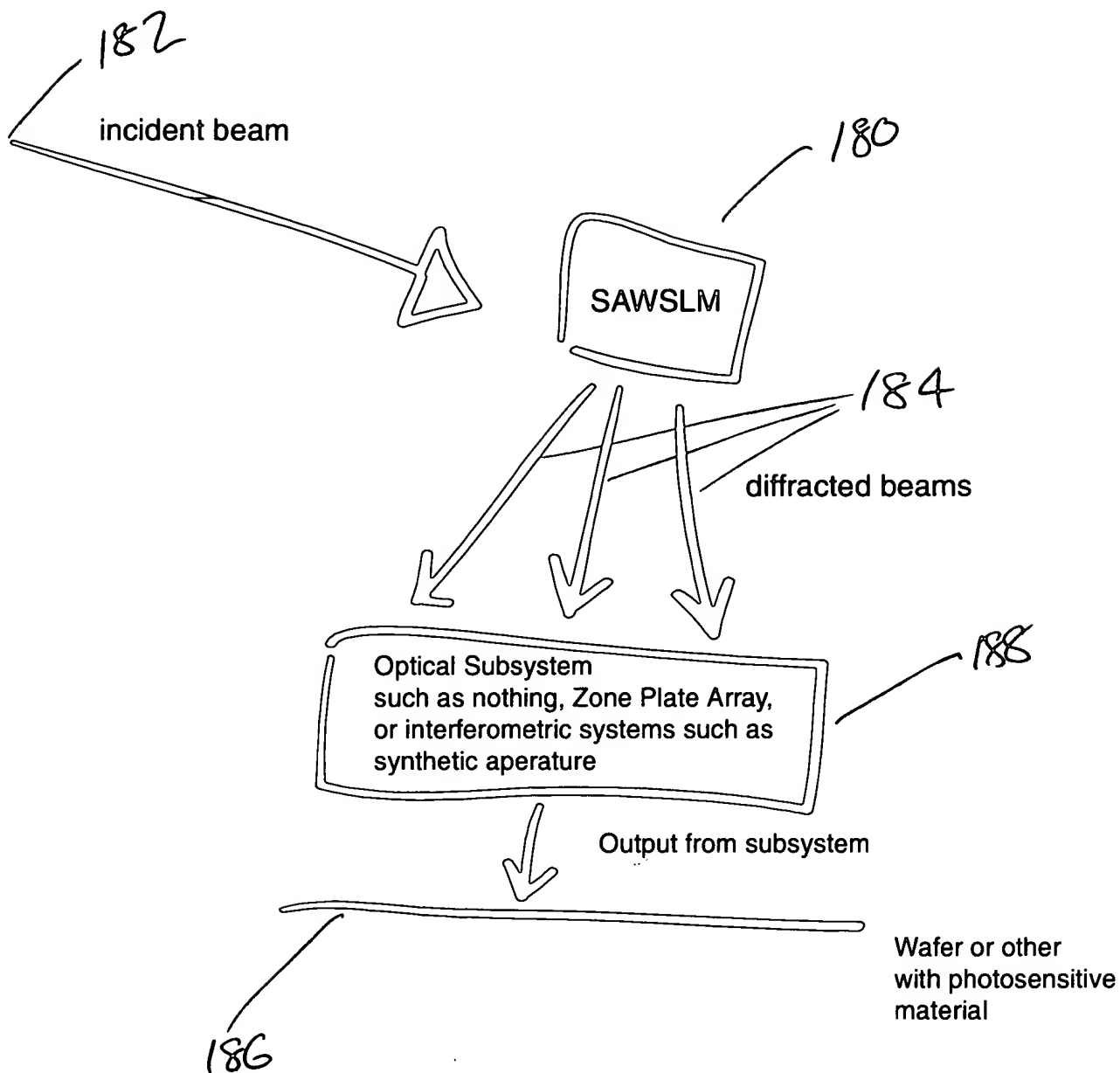


FIG 7

FIG. 8 is a schematic diagram of a SAW SLM as part of a lithographic system. The diagram shows an incident beam 182 entering a SAW SLM 180. The SAW SLM 180 produces diffracted beams 184, which are then directed to an optical subsystem 188. The optical subsystem 188 can be a zone plate array or an interferometric system such as a synthetic aperture. The output from the subsystem 188 is directed to a wafer or other photosensitive material 186.



SAW SLM as part of Lithographic System

FIG 8

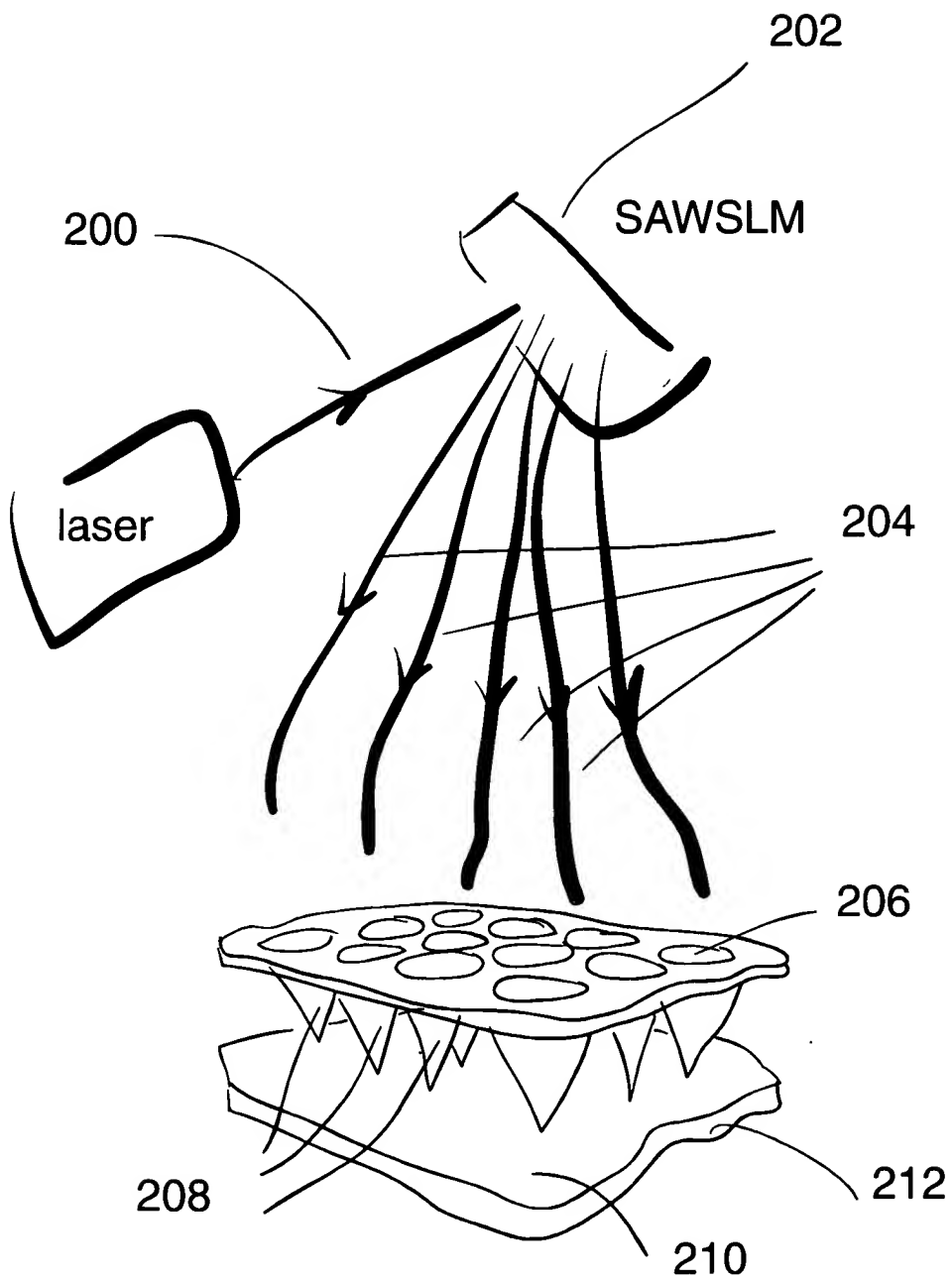


FIG 9

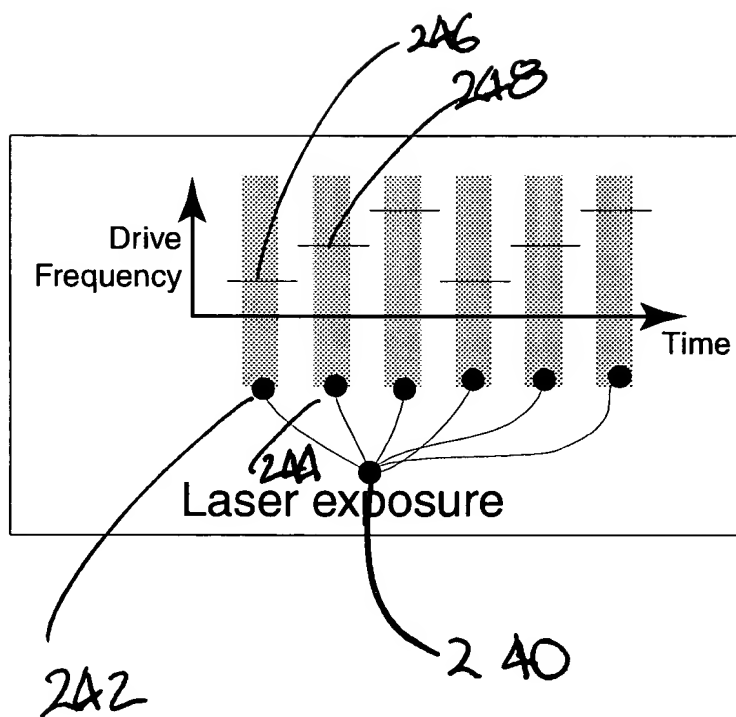


FIG 11

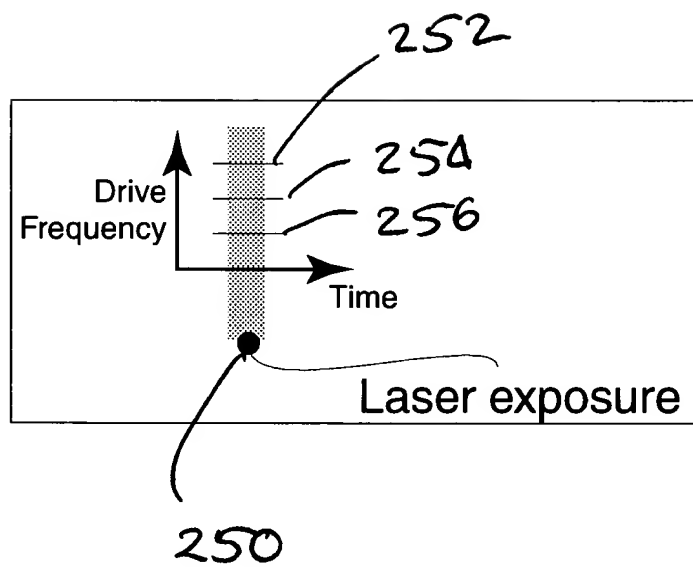
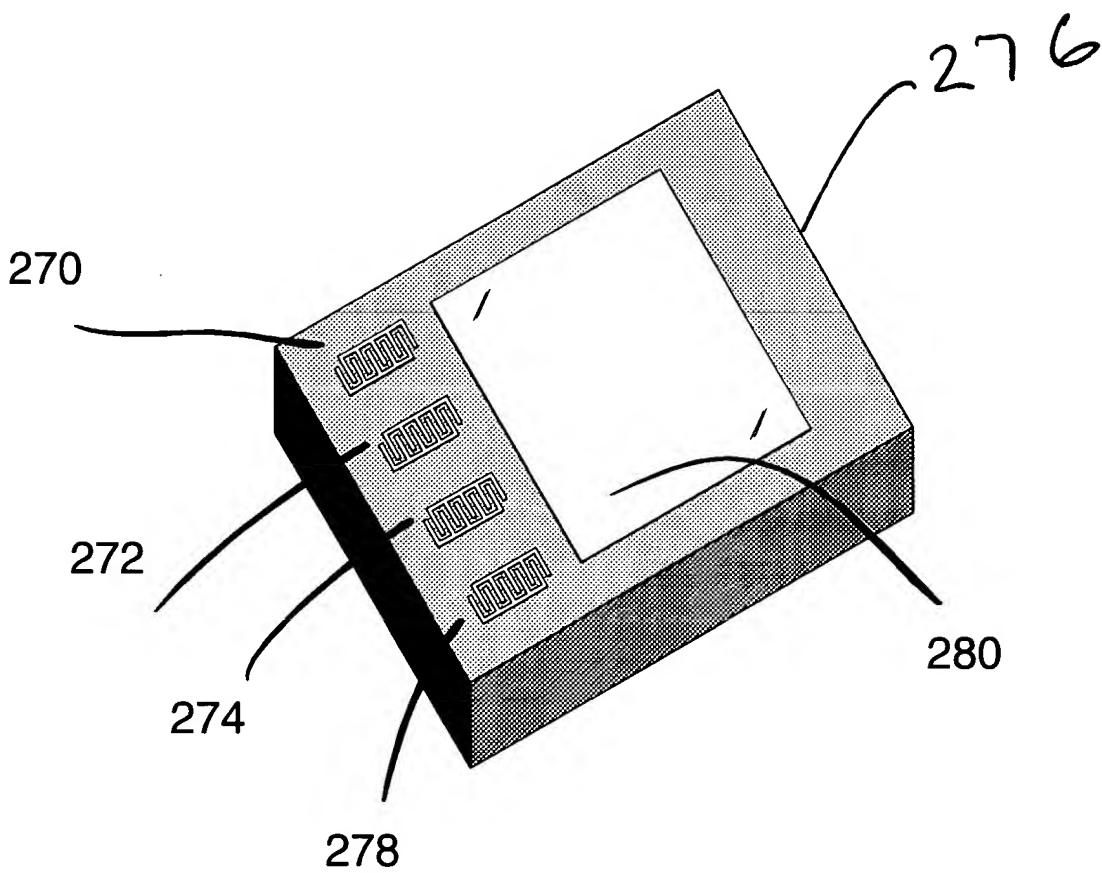


FIG 12

14



14

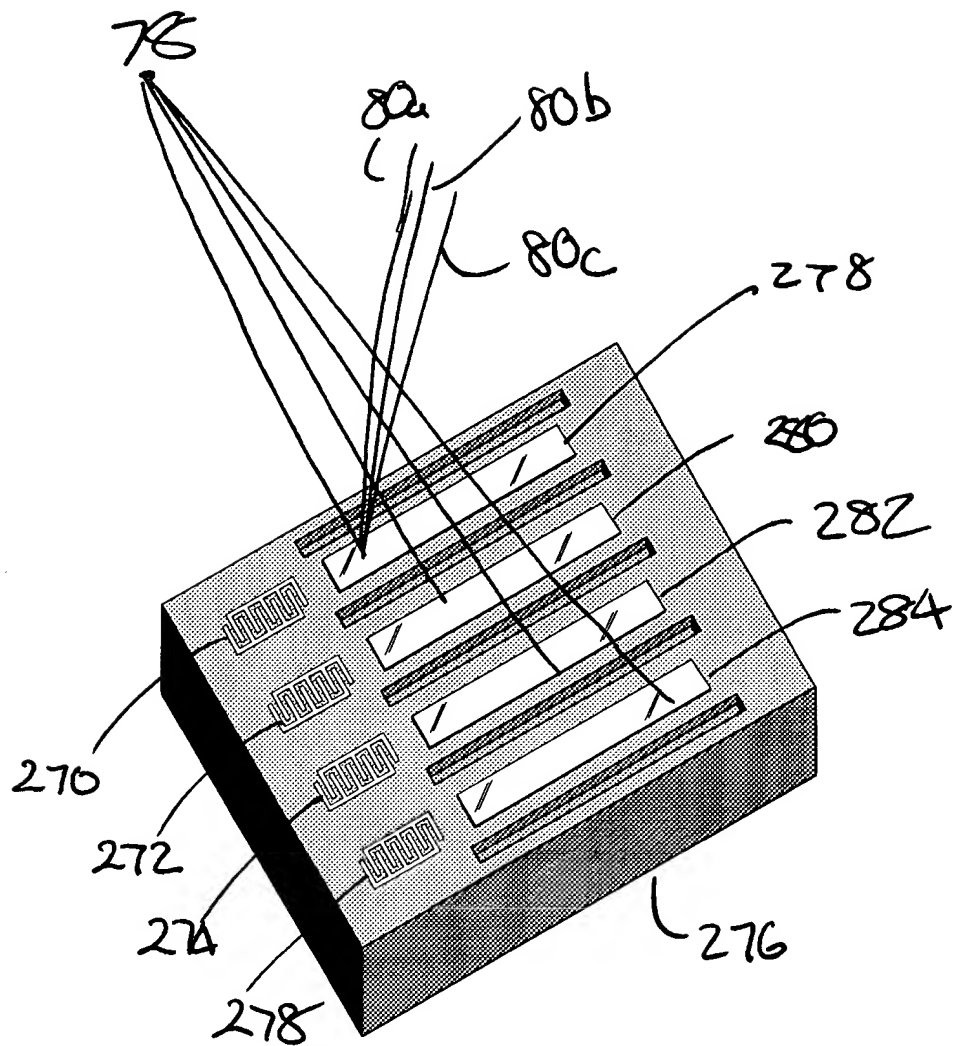


FIG 14b